

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of: Kanshi CHINONE

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Serial Number: Not yet assigned

(§371 of international application No. PCT/JP2004/011549)

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For: POLISHING SLURRY FOR SEMICONDUCTOR PLANARIZATION

Attorney Docket Number: 062110

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February 13, 2006

INFORMATION DISCLOSURE STATEMENT

Commissioner for Patents P. O. Box 1450 Alexandria, VA 22313-1450

Sir:

In compliance with 37 C.F.R. §1.56, Applicants direct the attention of the Patent and Trademark Office to the documents listed on the attached PTO/SB/08. A copy of each non- U.S. document is enclosed herewith.

If there are any fees due in connection with the filing of this paper, please charge Deposit Account No. <u>50-2866</u>.

Respectfully submitted,

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Enclosure: PTO/SB/08, 7 documents and international search report.

Complete if Known

New Application

February 13, 2006

Kanshi CHINONE

Combined Form PTO/SB/08A&B

INFORMATION DISCLOSURE STATEMENT BY APPLICANT

(use as	s many sheets as	necessary)		Art Unit		
·				Examiner Name		
Sheet	1	of	1	Attorney Docket Number	062110	
		-				

Application Number

Filing Date

Confirmation Number

First Named Inventor

U.S. PATENT DOCUMENTS					
Examiner Initials*	Cite No.1	Document Number		Publication Date	
		Number	Kind Code ² (if known)	MM-DD-YYYY	Name of Patentee or Applicant of Cited Document
		US			
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FOREIGN PATENT DOCUMENTS							
Examiner Initials*	Cite No.1	Foreign Patent Document			Publication Date	Name of Patentee or	
		Country Code ³	Number ⁴	Kind Code ⁵ (if known)	MM-DD-YYYY	Applicant of Cited Document	Translation ⁶
	1	JP	10-154673		06-09-1998	Hitachi Chem. Co., Ltd.	Abstract, cited in the ISR
	2	JP	2003-188122		07-04-2003	Sanyo Chem. Ind., Ltd.	Abstract, cited in the ISR
	3	JP	2003-171653		06-20-2003	Hitachi Chem Co., Ltd.	Abstract, cited in the ISR
	4	JP	2002-212544		07-31-2002	Mitsui Mining & Smelting Co., Ltd.	Abstract, cited in the ISR
	5	JP	2000-26840		01-25-2000	Toray Ind., Inc.	Abstract, cited in the spec.
	6	JP	2002-371267		12-26-2002	Mitsui Mining & Smelting Co., Ltd.	Abstract, cited in the spec.

Examiner Initials*	Cite No.1	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city, and/or country where published.	Translation ⁶
	7	Torajiro HONMA et al.; "Effect of Various Factors on Grinding Using Jet Mill", Chemical Engineering Paper Collection, Vol., 6, No. 5, pp.527-532, 1980. Cited in the spec.	Abstract
	8	International Search Report dated November 22, 2004 of PCT/JP2004/011549	

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^{*}EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

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